

O I P E Docket No.: 060188-0658

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Application of

Masashi HAMANAKA, et al.

Application No.: 10/671,502

Filed: September 29, 2003

: Customer Number: 20277

: Confirmation Number: 8488

: Group Art Unit: 3723

: Examiner: RACHUBA, MAURINA T

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For: POLISHING METHOD FOR SEMICONDUCTOR DEVICE, METHOD FOR
FABRICATING SEMICONDUCTOR DEVICE AND POLISHING SYSTEM

AMENDMENT

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated January 27, 2006, having a three-month shortened statutory period for response set to expire April 27, 2006, a one-month extension up to and including May 27, 2006 being filed concurrently herewith, please amend the above-identified application as follows.